Fig.1

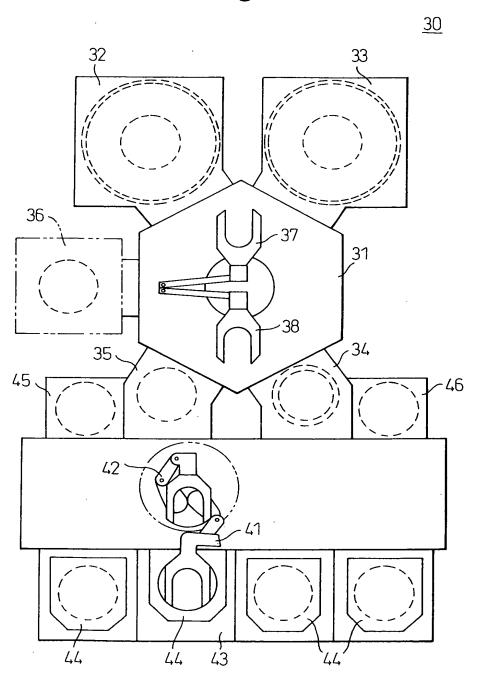


Fig.2

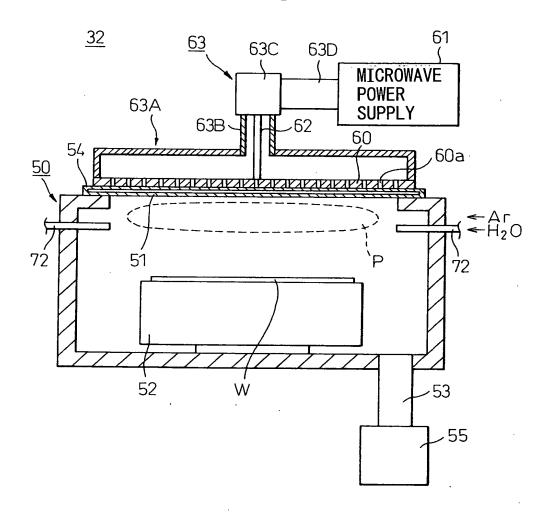


Fig.3

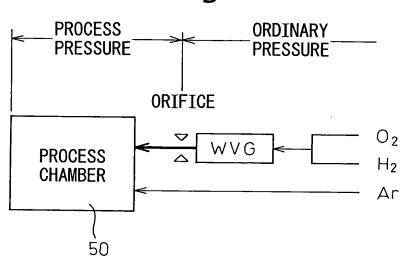


Fig.4

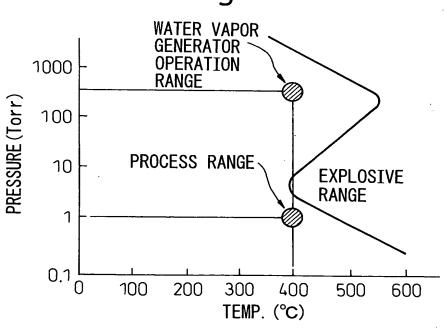
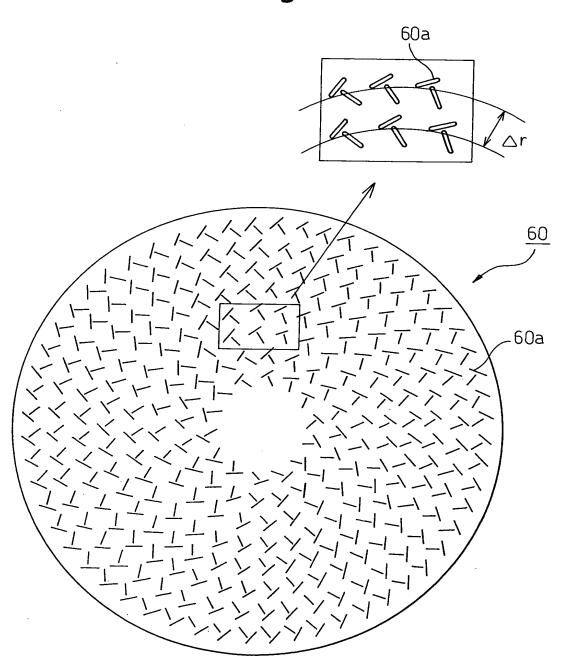
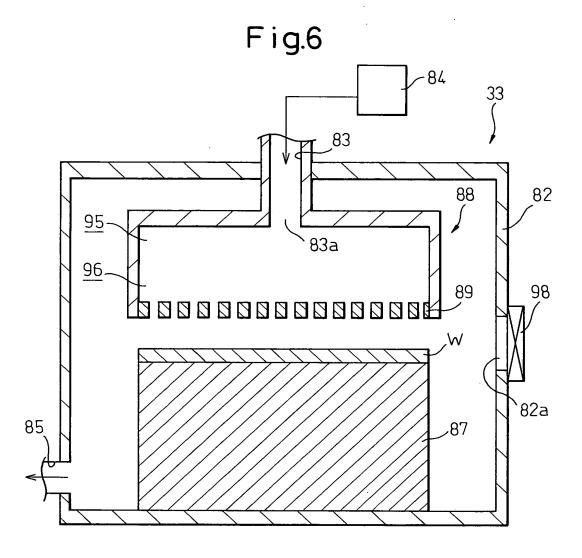
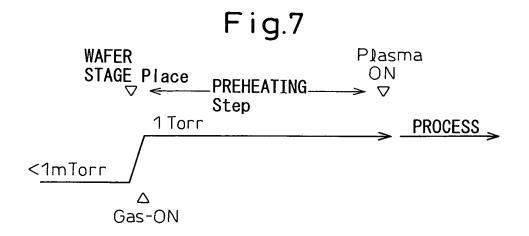
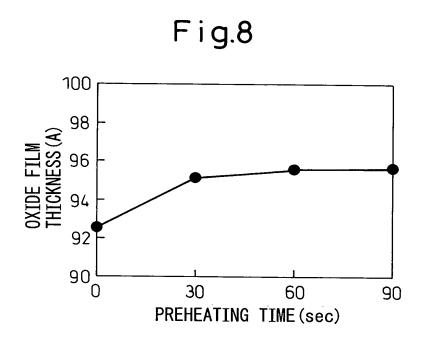


Fig.5









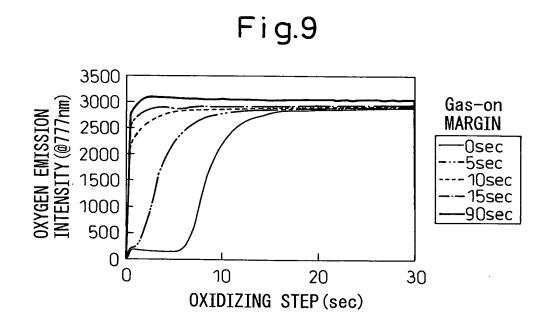


Fig. 10

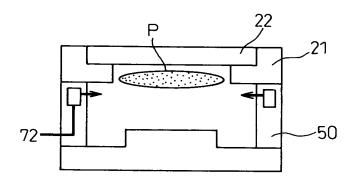
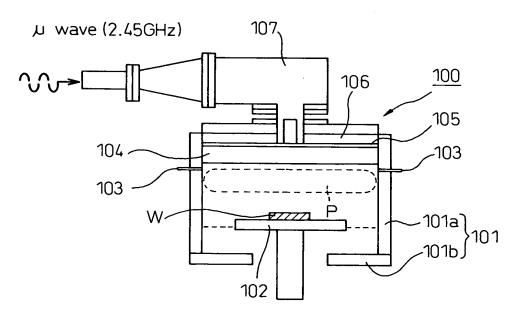
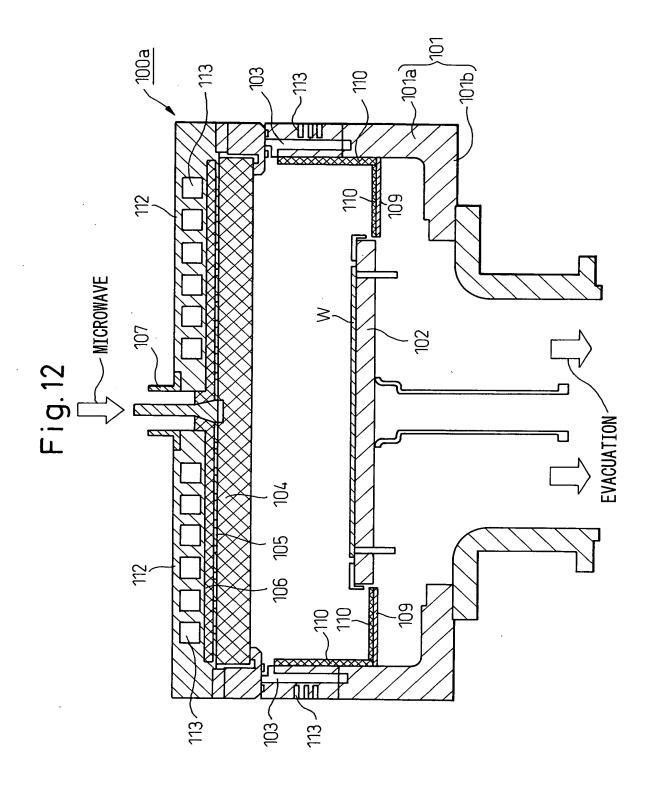


Fig.11





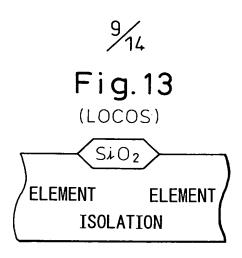


Fig. 14

TRENCH
SiO₂

ELEMENT
ISOLATION

(Sharrow Trench Isoration)

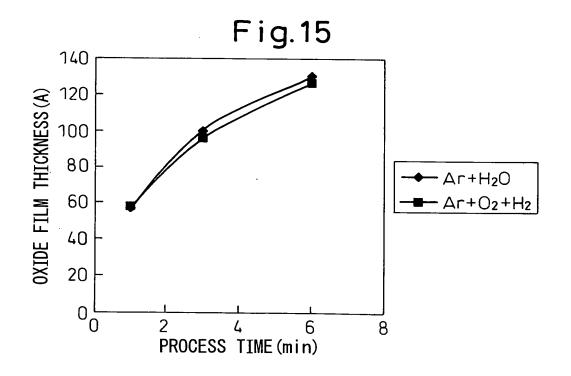
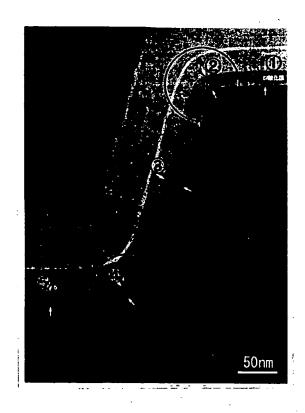
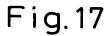


Fig. 16





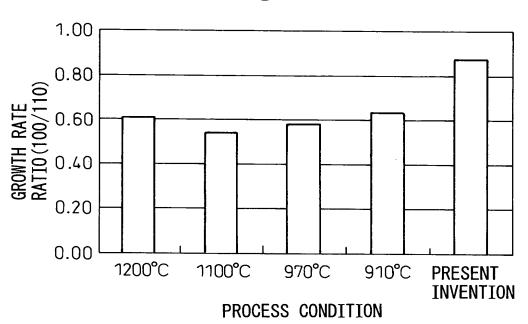


Fig. 18
NEGATIVE VOLTAGE APPLICATION

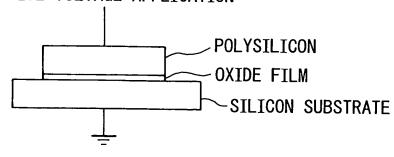
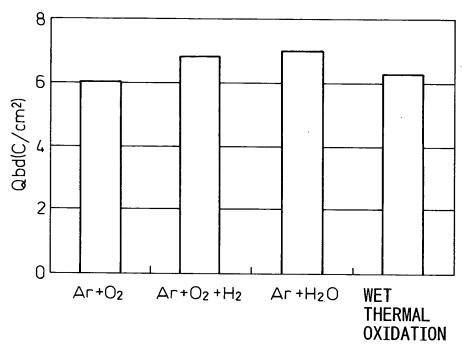


Fig. 19



PROCESS CONDITION

Fig.20A EMISSION SPECTRUM OF $Ar + O_2 + H_2$ PLASMA

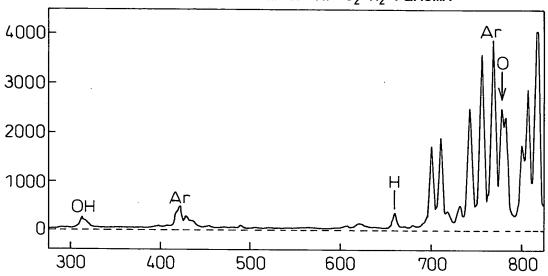


Fig.20B EMISSION SPECTRUM OF Ar+H₂O PLASMA

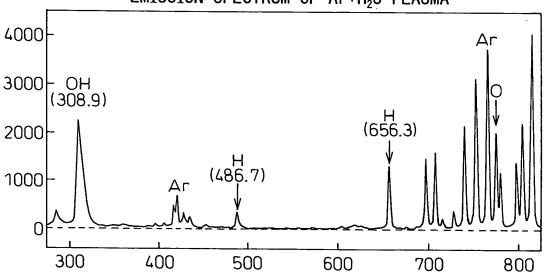


Fig.21

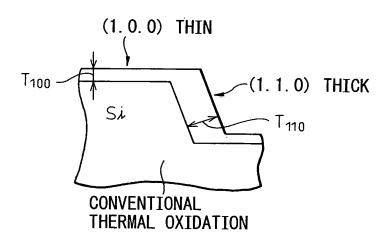


Fig.22

